 INFORMATION DISCLOSURE STATEMENT	<i>Complete if known</i>	
	Application Number: 10/076,858	
	Filing Date: February 14, 2002	
	First Named Inventor: Steinberg	
	Group Art Unit: 1775	
Examiner Name: Stephen J. Stein		Attorney Docket Number: R&H 03-19
SHEET 1 OF 1		

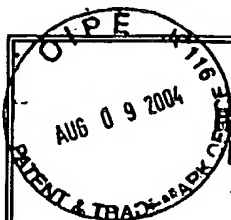
UNITED STATES PATENT DOCUMENTS				
EXAMINER'S INITIALS	CITE NO.	PATENT NUMBER	ISSUE DATE MM-DD-YYYY	FIRST NAMED INVENTOR
SJS		6595700	07/22/2003	Steinberg, et al.
SJS		6738145	05/18/2004	Sherrer, et al.
SJS		2001/0055460	12/27/2001	Steinberg

FOREIGN PATENT DOCUMENTS					
EXAMINER'S INITIALS	CITE NO.	DOCUMENT NUMBER	COUNTRY OR REGION	DATE OF PUBLICATION MM-DD-YYYY	FIRST NAMED INVENTOR OR APPLICANT
SJS		WO 03/027734	WO	04/03/2003	Jeantil, et al.

OTHER PRIOR ART - NON-PATENT DOCUMENTS		
EXAMINER'S INITIALS	CITE NO.	Include name of the author (in Capital Letters), title of the article (when appropriate), title of the item(book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published

EXAMINER'S SIGNATURE		DATE CONSIDERED	9/4/04
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SJS		4810557	03/07/1989	Blonder
SJS		4837129	06/08/1989	Frisch et al.
SJS		4863560	09/05/1989	Hawkins
SJS		4904036	02/27/1990	Blonder
SJS		4938841	07/03/1990	Shahar et al.
SJS		4957592	09/18/1990	O'Neill
SJS		5338400	08/16/1994	Jerman
SJS		5478438	12/26/1995	Nakanishi et al.
SJS		5479426	12/26/1995	Nakanishi et al.
SJS		5611006	03/11/1997	Tabuchi
SJS		5911021	06/08/1999	MacDonald et al.
SJS		6132107	10/17/2000	Morikawa
SJS		6187515	02/13/2001	Tran et al.
SJS		6257772	07/10/2001	Nakanishi et al.
SJS		6553173	04/22/2003	Gotō
SJS		6567590	05/20/2003	Okada et al.
SJS		US 2002/0195417	12/26/2002	Steinberg
SJS		US 2003/0020130	01/30/2003	Steinberg et al.
SJS		US 2003/0067069	04/10/2003	Steinberg et al.
SJS		US 2003/0021572	01/30/2003	Steinberg

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OTHER PRIOR ART - NON-PATENT DOCUMENTS

EXAMINER'S INITIALS	CITE NO.	Include name of the author (in Capital Letters), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published
SJS		Nijdam, et al. "Etching of silicon in alkaline solutions: a critical look at the {111} minimum," MESA
SJS		Oosterbroek, et al. "New design methodologies in <111> oriented silicon wafers," MESA
SJS		Suchtelen, et al. "Simulation of Anisotropic Wet-Chemical Etching Using a Physical Model," MESA

EXAMINER'S SIGNATURE

Stephen J. Stein

DATE CONSIDERED

9/4/2004

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